



01-92-04

PTO/SB/21 (08-03)

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FORM

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		Application Number	10/664,738
		Filing Date	09/18/2003
		First Named Inventor	Janos Fucska
		Art Unit	1763
		Examiner Name	Unknown
Total Number of Pages in This Submission		Attorney Docket Number	MI22-2271

ENCLOSURES (Check all that apply)		
<input type="checkbox"/> Fee Transmittal Form <input type="checkbox"/> Fee Attached	<input type="checkbox"/> Drawing(s) <input type="checkbox"/> Licensing-related Papers <input type="checkbox"/> Petition <input type="checkbox"/> Petition to Convert to a Provisional Application <input type="checkbox"/> Power of Attorney, Revocation <input type="checkbox"/> Change of Correspondence Address <input type="checkbox"/> Terminal Disclaimer <input type="checkbox"/> Request for Refund <input type="checkbox"/> CD, Number of CD(s) _____	<input type="checkbox"/> After Allowance communication to Technology Center (TC) <input type="checkbox"/> Appeal Communication to Board of Appeals and Interferences <input type="checkbox"/> Appeal Communication to TC (Appeal Notice, Brief, Reply Brief) <input type="checkbox"/> Proprietary Information <input type="checkbox"/> Status Letter <input checked="" type="checkbox"/> Other Enclosure(s) (please identify below): Return Receipt Postcard PTO-1449, cited references
Remarks Customer No. 021567 No fee is required with this filing. However, should a fee be determined as owing, charge such fee to Deposit Account No. 23-0925.		

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Firm or Individual name	Mark S. Matkin, Reg. No. 32,268 Wells St. John P.S.
Signature	
Date	12/31/03

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EL979951384

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 10/664,738
Filing Date September 18, 2003
Inventor Fucsko et al.
Assignee Micron Technology, Inc.
Group Art Unit 1763
Examiner Unknown
Attorney Docket No. MI22-2271
Title: Methods of Etching Silicon Nitride Substantially Selectively Relative to an Oxide of Aluminum and Methods of Forming Trench Isolation Within a Semiconductor Substrate



SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References - See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. Copies of the cited art are attached hereto. No admission is made regarding whether all the submitted references are prior art.

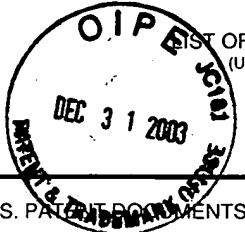
This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing of a first Office Action on the merits, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: 12-31-03

By: 
Mark S. Matkin
Reg. No. 32,268

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-2271		SERIAL NO. 10/664,738		
 LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT: Micron Technology, Inc.				
		FILING DATE September 18, 2003		GROUP 1763					
U.S. PATENT DOCUMENTS									
*Examiner's Initials		Document Number	Date	Name		Class	Subclass	Filing Date If Appropriate	
	AA								
	AB								
	AC								
	AD								
	AE								
	AF								
	AG								
	AH								
	AI								
FOREIGN PATENT DOCUMENTS									
		Document Number	Date	Country		Class	Subclass	Translation	
								Yes	No
	AJ								
	AK								
	AL								
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
	AM		B. Garrido et al., "The Role of Chemical Species in the Passivation of <100> Silicon Surfaces by HF in Water-Ethanol Solutions", J. Electrochem. Soc., Vol. 143, No. 12, December 1996, pp. 4059-4066.						
	AN		Wood et al., "Etching Silicon Nitride and Silicon Oxide Using Ethylene Glycol / Hydrofluoric Acid Mixtures",						
			Electrochemical Society Proceedings Volume 99-36, pp. 258-263.						
	AO		Knotter et al., "Etching Mechanism of Silicon Nitride in HF-Based Solutions", J. Electrochem. Soc., 148 (3),						
			2001, pp. F43-F46.						
EXAMINER		DATE CONSIDERED							
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	AA								
	AB								
	AC								
	AD								
	AE								
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	AG								
	AH								
	AI								
FOREIGN PATENT DOCUMENTS									
		Document Number	Date	Country		Class	Subclass	Translation	
								Yes	No
	AJ								
	AK								
	AL								
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
	AM		T. Kezuka et al., "The Control of Etching Rate for Various SiO ₂ Films", Electrochemical Society Proceedings,						
			Vols. 99-36, 2000, pp. 244-251.						
	AN								
	AO								
EXAMINER		DATE CONSIDERED							
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